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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10010945	FILING DATE 12/06/2001	CLASS 448	SUBCLASS 1	GAU 1763	EXAMINER M. J.
**APPLICANTS: Shibata Tomohiko; Nakamura Yukinori; Tanaka Mitsuhiro;					
**CONTINUING DATA VERIFIED: for New					
** FOREIGN APPLICATIONS VERIFIED: JAPAN 2000-377,547 12/12/2000 JAPAN 2001-340,945 11/06/2001 ghm					
PG-PUB <input type="checkbox"/>		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiners's initials <i>ghm</i>				ATTORNEY DOCKET NO 782 204	
TITLE : Method for fabricating a III-V nitride film and an apparatus for fabricating the same					
U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	
		Print Claim for O.G.	
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
		Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER		Application Examiner	
		PREPARED FOR ISSUE	
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